



MEMS and Reliability

Microelectromechanical Systems

18-849b Dependable Embedded Systems

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Required Reading:

Reliability and Long Term Stability of MEMS, S.B.Brown et. al. 1996

Materials Reliability in MEMS Devices, S.B. Brown et.al. 1997

Best Tutorial:

Microelectromechanical Systems(MEMS) Tutorial, Kaigham J. Gabriel

http://mems.isi.edu/archives/otherWWWsites_tutorial.html

Authoritative Books:

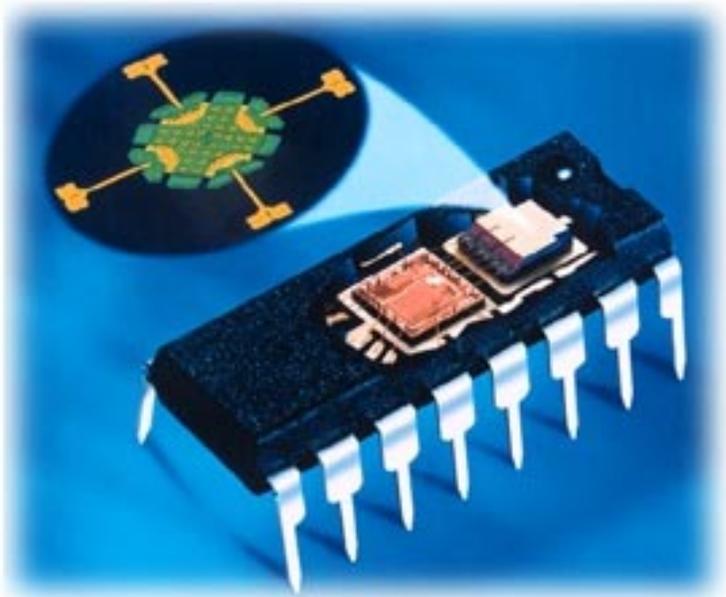
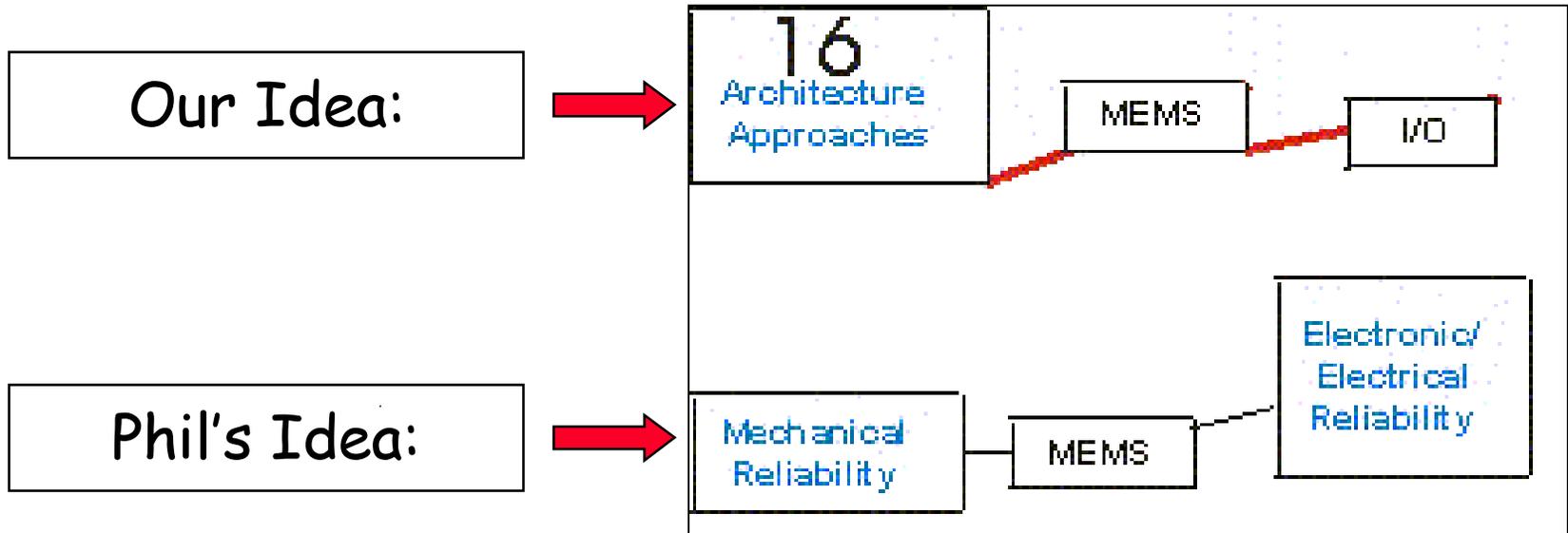
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Movie Gallery:

<http://www.mdl.sandia.gov/Micromachine/movies.html>

**Carnegie
Mellon**

You Are Here



Courtesy of Motorola Corp.

Introduction



◆ What is MEMS(MicroElectroMechanical Systems)

- Microelectromechanical systems (MEMS):
 - are integrated micro devices or systems
 - combine electrical and mechanical components
 - are fabricated using integrated circuit (IC) compatible batch-processing techniques
 - range in size from micrometers to millimeters.
 - can sense, control, and actuate on the micro scale
 - can function individually or in arrays to generate effects on the macro scale.
- Revolutionizing “traditional” mechanical and materials engineering into “high-tech”.
- The next logical step in the silicon revolution.
- \$10 Billion market today, \$34 Billion market in 2002
- Fascinating, amazing, ...

◆ DARPA MEMS program Goal:

- co-located perception, processing and control

Applications: Size DOES Matter



- ◆ **Optical switching:**
 - Integrated Optics, Micro-optics
- ◆ **Embedded sensors & actuators**
 - Inertial: accelerometers that deploy car airbags
 - Pressure
- ◆ **Biomedical devices**
 - [Non-invasive biomedical sensors](#)
- ◆ **Microfluidics**
 - Inkjet-printer cartridges
 - Miniature analytical instruments
 - Chip-based DNA processing & sequencing
 - Propellant and combustion control
 - Chemical factories on chip
- ◆ **Mass data storage**
 - Terabytes per square centimeter
- ◆ **Low-power, high-resolution small displays**
- ◆ **Microinstruments & Micromachines**
 - Micropumps
- ◆ **Microrobots**

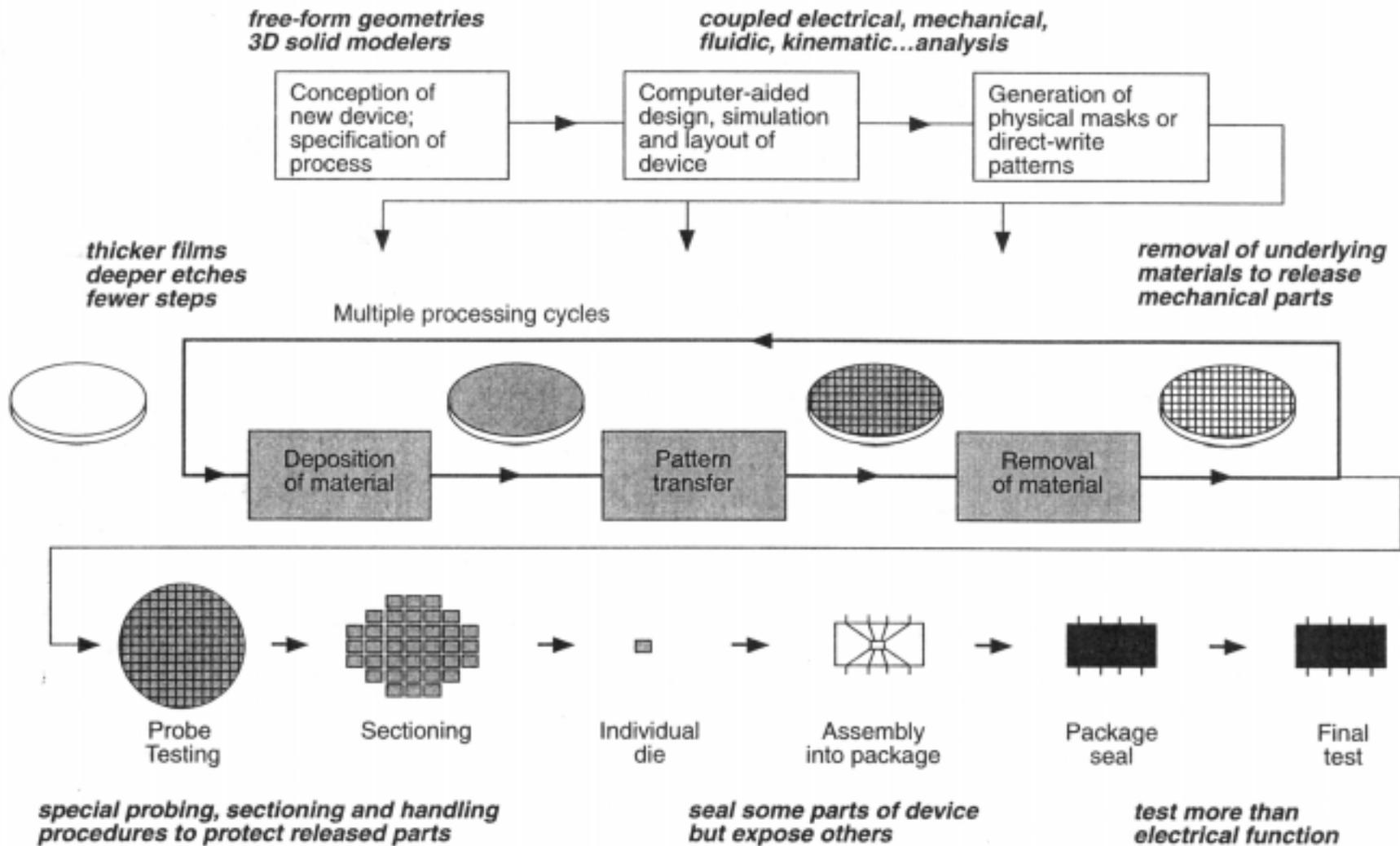
MEMS Fabrication



- ◆ **“System on a chip”**: a miniature embedded system itself
 - Including computing, sensing and actuating parts
 - Similar to IC manufacturing process
 - Usually fabricated completely assembled -- no piece parts
- ◆ **Characteristics of Fabrication**
 - Miniaturization
 - Multiplicity
 - Microelectronics
- ◆ **Fabrication methods and materials**
 - Bulk micromachining
 - Wafer-to-wafer bonding
 - High-aspect ratio micromachining
 - **Surface micromachining**

Fabrication Procedures

- ◆ Significant distinctions between MEMS and ICs are noted in bold italics.
- Source: Electronics Technology Office, DARPA

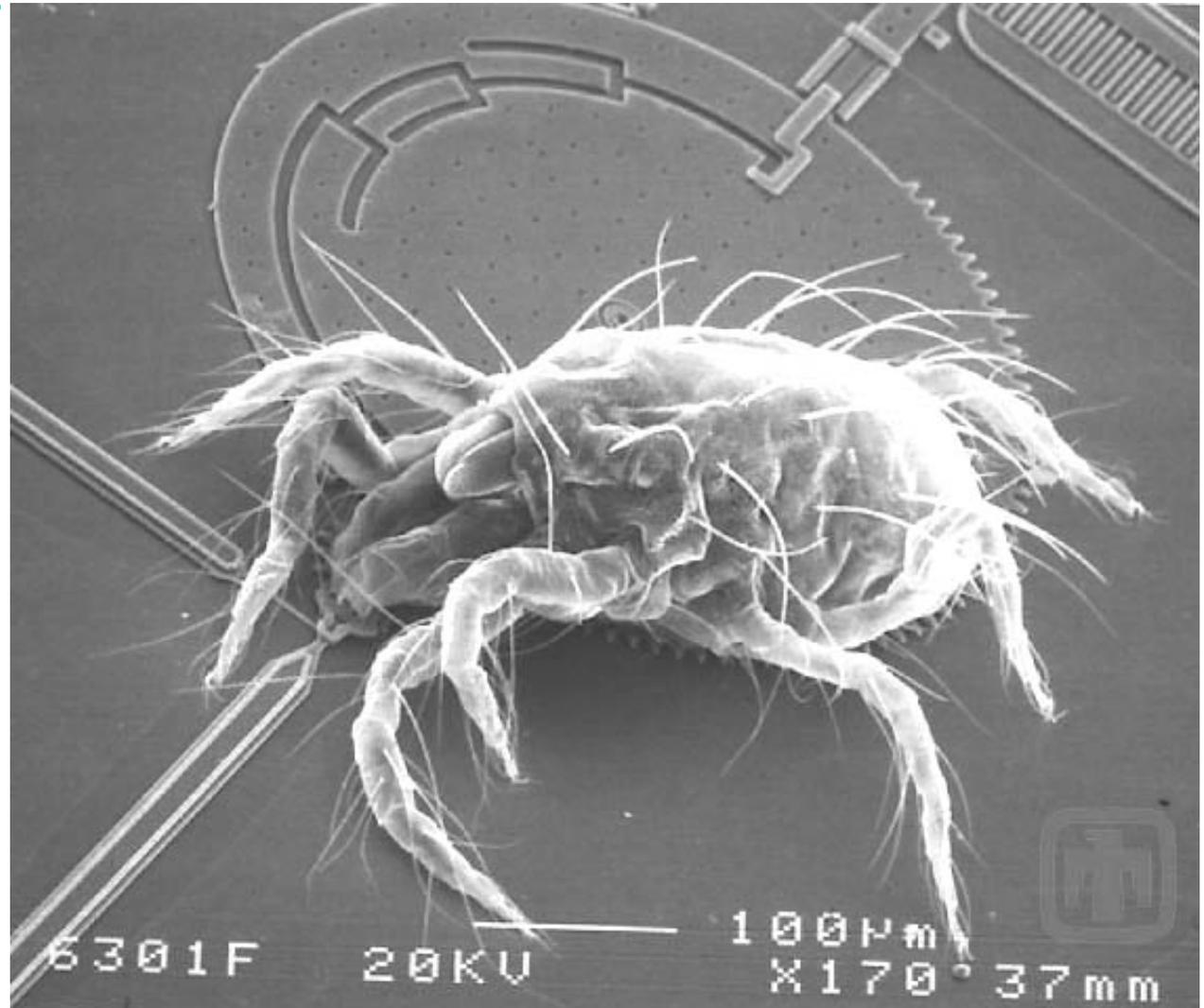


Typical Size

- ◆ “The technologies and applications of three-dimensional devices with sizes in the micrometer ranges.”

- ◆ **Spider mite raids microlock**

- This is not Godzilla. This is a spider mite (a miniscule, white fleck to the human eye) hanging out on a microlock mechanism. Note the scale key in the lower right corner.



Reliability of MEMS



- ◆ **More than just Electro+Mechanical failures**
 - Mechanical reliability
 - Electrical reliability
 - Material reliability
 - Interactions of mechanical and electrical part
- ◆ **Macro failure modes not applicable**
- ◆ **Unique failure modes at microscopic level**
 - Static overload
 - Delamination
 - Creep
 - Environmental attack
 - Fatigue

Root Causes



◆ Capillary forces

- Liquid-air interface induced in etching
- Stiction happens even without liquid; aggravated by moisture

◆ Operational Methods

- Drive signals not comply to mechanical model
 - e.g. MEMS actuators driven by model based drive signals have 5 orders of magnitude longer life than square wave signals in experiment.
- Noise in drive signals

◆ Mechanical Instabilities

- Gear position, spring shape, alignment, etc
- Buckling

◆ Electrical Instabilities

- Linear clamping caused by static electricity

Techniques for Higher Reliability



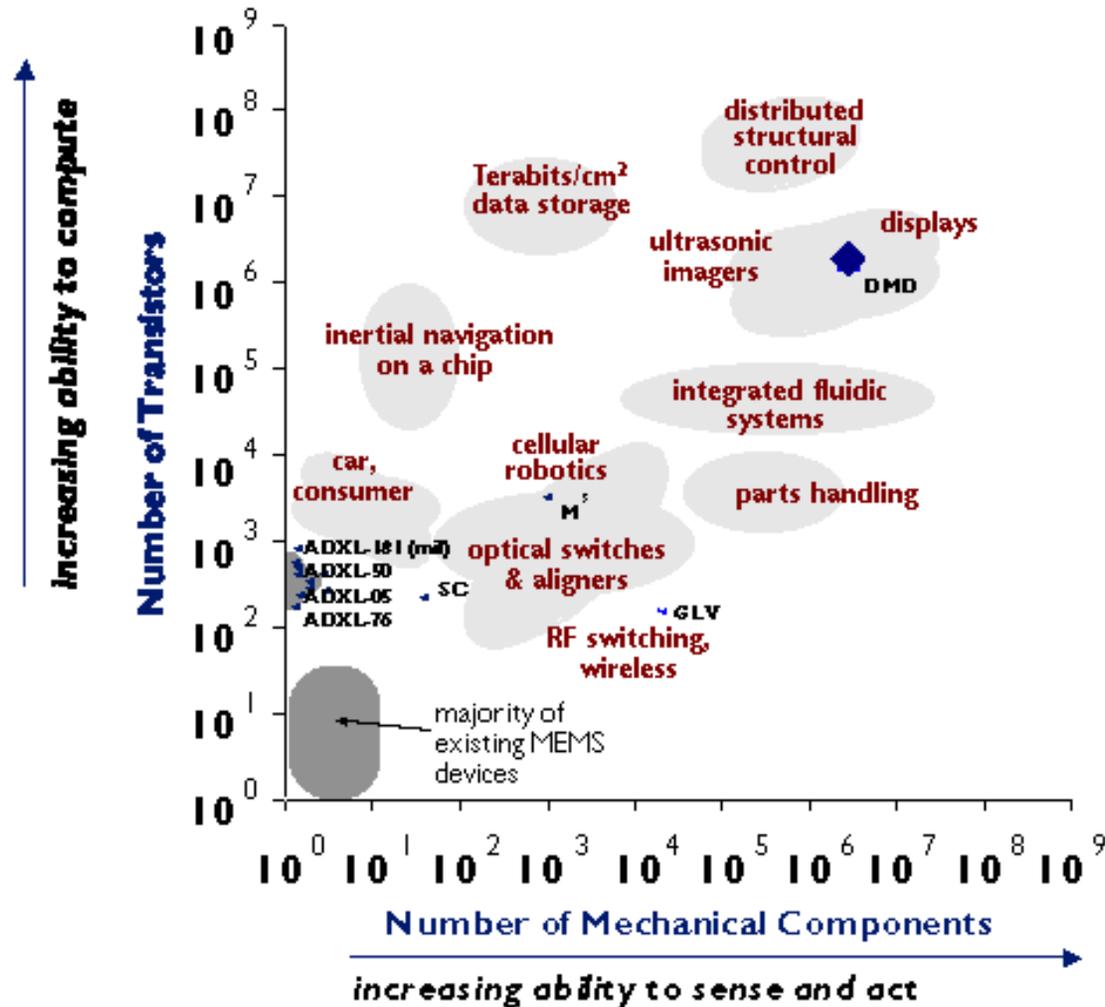
- ◆ **Chemical surface treatments**
 - Super-critical drying method
 - Hydrophobic coating
- ◆ **Model-based operational methods**
 - Optimized electrical drive signals
 - Minimized constraint forces
- ◆ **Clever design modifications**
 - Improved thickness, stiffness, endurance, shape, etc

Conclusions



- ◆ **Revolutionary, fast growing new technology**
- ◆ **Still in its infancy**
 - Like IC technology 30 years ago
- ◆ **Reliability: How MEMS fail is not well understood**
 - Study shows material strength is **NOT** a key factor
 - failures induced by deficiencies in material/mechanical properties not majority, such as fracture strength or fatigue-related fracture
 - Failures causes typically related to contacting or rubbing surfaces: Stiction and friction-related wear
 - Unique failure modes at microscopic level
 - Static overload, Delamination, Creep, Environmental attack, Fatigue
 - Reliability can be enhanced by optimized designs and better techniques

Future Direction



Trends in electromechanical integration

Log-log plot of number of transistors merged with number of mechanical components for existing and future MEMS devices and systems.

On the Reading Papers



- ◆ ***Reliability and Long-Term Stability of MEMS***
 - High-level generalization of MEMS failure modes
 - Different failure modes in microscope v.s. macroscope

- ◆ ***Materials Reliability in MEMS Devices***
 - An accelerated testing technique on stress/fatigue testing
 - Found fatigue life of poly is a function of stress
 - Previous work found crack growth dependent on moisture